Hydrogen Peroxide Gas for Thin Film Processing

Increase surface hydroxylation, lower process temperatures & increase choice in precursors

BRUTE® Peroxide 2 Series is the next generation product from RASIRC® to deliver concentrated hydrogen peroxide (H_2O_2) gas for Atomic Layer Deposition (ALD), Area Selective Deposition (ASD), and other processes that require controlled delivery of H_2O_2 gas with minimal water. This improved version of BRUTE® Peroxide delivers gas from a solid source and has superior output and longer shelf life than previous BRUTE® Peroxides. Design advantages include improved output stability, concentration, purity, and safety. H_2O_2 molecules pre-loaded onto the proprietary solid sorbent in an engineered vaporizer that is designed specifically for the stable storage and delivery of H_2O_2 gas for high purity applications. BRUTE® Peroxide 2 Series simplifies having to store or handle high concetration liquid peroxide.

Background

Oxidants such as oxygen, water, oxygen plasma, and ozone have all been used for cleaning, stripping, hydroxylation, and oxidation in thin film processes. However, with shrinking thermal budgets, oxygen, plasma, and water are not as effective as they once were. Ozone and plasma can be difficult to control, can cause surface and subsurface damage, and generate non-uniformities in High Aspect Ratio (HAR) structures.

With BRUTE® Peroxide 2 Series, H_2O_2 is now a superior alternative to these older methods. H_2O_2 has a rapid and straightforward reaction pathway. BRUTE® Peroxide overcomes historical concentration control issues of water in the H_2O_2 source.

Typical water/ H_2O_2 solutions produce relatively low H_2O_2 gas concentrations. Water has significantly higher vapor pressure compared to H_2O_2 . This leads to a high concentration of water in the headspace, which is ultimately delivered to the chamber.

Frequently overestimated, the H_2O_2 gas concentration in the headspace above a 30 wt% H_2O_2 solution is only 25 ppm, not 30%. The molar ratio of H_2O_2 to water is 1:181 at 0°C, 760 torr.

Prior to BRUTE® Peroxide commercialization, the majority of technical publications frequently concluded that there was minimal process difference between $\rm H_2O_2$ and water. However, the studies failed to deliver enough $\rm H_2O_2$ to demonstrate the superiority of $\rm H_2O_2$ to water in the process.

BRUTE® Peroxide Benefits

- Provides stable delivery of H₂O₂ gas with minimal water.
- It is not a nebulizer, which releases liquid droplets of H₂O₂/H₂O and leads to non-uniformity, spotting, and particulates.
- Allows for differentiation between H₂O₂ and water vapor in process reactions.
- Alternative to water, ozone, or oxygen plasma.
- Improves compatibility with metal surfaces—less aggressive oxidant than ozone or Oxygen Plasma.
- H₂O₂ is self limiting, once it reacts with all open active sites on the surface, the reaction ends.
- Enables ambient delivery of H₂O₂ gas without the need for additional heating related decomposition.
- Reacts faster and at lower temperatures than water.
- Superior surface density hydroxylation with minimal subsurface oxidation.
- Superior penetration into 3D and HAR microstructures compared to water.
- Allows for high concentration H₂O₂ delivery into vacuum and low-pressure applications.
- Increases interface hydroxyl density on substrates such as Si, Ge, and SiO₂.
- · Proprietary delivery process, ensuring higher purity.
- Overcomes Raoult's Law to provide constant mass flow rate as source is consumed.



Page

220

320

Bond Dissociation Energy

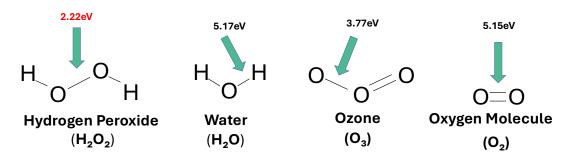


Figure 1: The low dissociation energy of hydrogen peroxide's oxygen-oxygen bond makes H₂O₂ more reactive than conventional oxidants.

OES Spectra of Various Oxidant

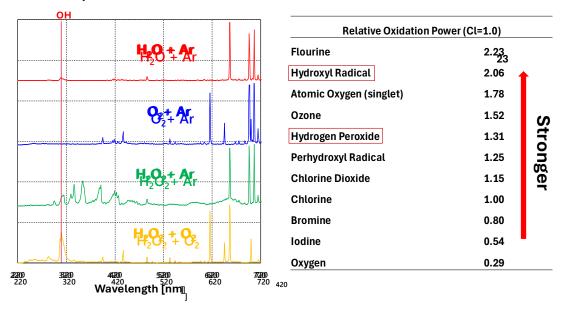


Figure 2: Hydrogen peroxide has a hydroxyl density 10x higher than water plasma, leading to easier access to hydroxyl radicals that have a higher oxidation potential than atomic oxygen.

Table 1: P/N: 100955 Ampoule Index

Index	Description	Size/Type
А	Insert Gas Inlet	1/4″ Male VCR*
В	Process Gas Outlet	1/4" Male VCR
С	Vent Relief Port	9/16-18 UNF
D	Grounding Cable Assembly	18" length of wire with MF Terminal Ring (included with vaporizer) Part #201990

^{*}VCR is registered trademark of Swagelok

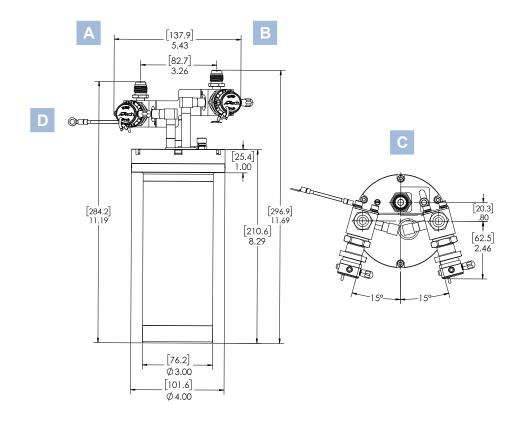


Figure 3: P/N 100955 Ampoule Design, 235 Gram Fill

Table 2: BRUTE® Peroxide vs. H₂O₂/H₂O Solutions

Solution Concentration (weight percent peroxide)	H ₂ O ₂ Concentration (ppm)	H ₂ O Concentration (ppm)
30	203*	24,131*
50	533*	17,143*
70	1,142*	9,241*
BRUTE® Peroxide 2 Series	2,248**	1,128**

^{*}Theoretical values based upon 25C and 760 torr per Raoult's Law.

Table 3: Specifications

Operating Conditions	 Temperature: 15-40°C Pressure Range: 0-1520 torr 		
Carrier Gas Requirements (if used)	 0-2000 sccm (user controlled MFC) STP: 0°C and 760 torr Filtered to 0.003 μm Purified to <1 ppb contaminates CDA, Oxygen, Nitrogen, or inert gas 		
Vaporizer Output	• ≥10mg/min at 20C and 100 torr with 500 sccm carrier gas		
Tools & Supplies Required	 PPE (see SDS for BRUTE® Peroxide RASIRC® P/N 900966) (2) 1/4" SS VCR gaskets no silver plating (Swagelok PN: SS-4-VCR-2-VS) 3/4" and 5/8" wrenches 		
Shelf Life	 12 weeks at 25°C 12 months if stored at 0-10°C 		
Vent Relief Cracking Pressure	Vessel will relieve pressure when above 25.0 psig		

^{**}Measured at 25C and 760 torr carrier gas flowrate of 1000 SCCM.

Table 4: BRUTE® Peroxide Chemistry

Name	Mass Loading	Part Number
BRUTE® Peroxide 450 Form Vessel	235g	110232-235G
OEM Form Vessel	400-500g	Contact RASIRC®

How to Order

To place an order for **BRUTE® Peroxide**:

- 1. Use Table 4 to identify the part number for the desired chemistry weight (g)
- 2. Contact RASIRC® at sales@rasirc.com

About RASIRC®

RASIRC® products generate and deliver water vapor, hydrogen peroxide, and hydrazine gas to enable critical processes.



Page 5